


EE C247B - ME C218 Introduction to MEMS Design Spring 2017

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Lecture Module 9: Energy Methods

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Lecture Outline

- Reading: Senturia, Chpt. 10
- Lecture Topics:
 - ↳ Energy Methods
 - Virtual Work
 - Energy Formulations
 - Tapered Beam Example

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Energy Methods

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More General Geometries

- Euler-Bernoulli beam theory works well for simple geometries
- But how can we handle more complicated ones?
- Example: tapered cantilever beam
- Objective: Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$

Top view of cantilever's $W(x)$

$W(x) = W\left(1 - \frac{x}{2L_c}\right)$

50% taper


$x = L_c$

F

x

y

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Solution: Use Principle of Virtual Work

- In an energy-conserving system (i.e., elastic materials), the energy stored in a body due to the quasi-static (i.e., slow) action of surface and body forces is equal to the work done by these forces ...
- Implication: if we can formulate **stored energy** as a function of the deformation of a mechanical object, then we can determine how an object responds to a force by determining the shape the object must take in order to **minimize** the **difference U** between the stored energy and the work done by the forces:

$$U = \text{Stored Energy} - \text{Work Done}$$

- Key idea: we don't have to reach $U = 0$ to produce a very useful, approximate analytical result for load-deflection

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More Visual Description ...

Same problem as before: Take a beam & apply a force:

- ① Apply force.
- ② Beam responds by bending.
- ③ This force has done work: $W = F \cdot y(Lc)$
- ④ Strain generated → This means the beam has received an influx of stored energy


⑤ Then:

$$U = \text{Stored Energy} - \text{Work Done} \rightarrow 0$$

(When we choose the right shape! (This is how we get the beam's response to F !))

magnitude determined by its deformed shape

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Fundamentals: Energy Density

- Strain energy density: [J/m³] $W(Q) = \int_0^Q \frac{Q}{C} dQ \rightarrow$ charging a capacitor from 0 \rightarrow Q takes this much work
 \rightarrow stored energy on a capacitor
 \rightarrow To find work done in straining material

This is a definition, so really can just say it's a definition.

$$W = \int_0^{\epsilon_x} \sigma_x d\epsilon_x \quad \text{x-axis normal stress term}$$


$\sigma_x(\epsilon_x) \rightarrow$ relates stress to strain @ position (x, y, z)
 $\sigma_x = E\epsilon_x \Rightarrow W = \int_0^{\epsilon_x} E\epsilon_x d\epsilon_x = \frac{1}{2} E\epsilon_x^2$

$W(q) = \int_0^q e(q) dq$ $q = \text{displacement}$ $e = \text{effort}$ } Generic Definition of Work

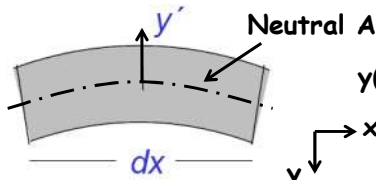
- Total strain energy [J]:
 \rightarrow Integrate over all strains (normal and shear)

$$W = \iiint \left(\frac{1}{2} E(\epsilon_x^2 + \epsilon_y^2 + \epsilon_z^2) + \frac{1}{2} G(\gamma_{xy}^2 + \gamma_{xz}^2 + \gamma_{yz}^2) \right) dV$$

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Bending Energy Density



$y(x) = \text{transverse displacement of neutral axis}$

- First, find the bending energy dW_{bend} in an infinitesimal length dx : W = width


$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \epsilon_x^2(y') dy'$$

$$\left[\frac{1}{R} = \frac{d^2 y}{dx^2}, \epsilon_x = \frac{y'}{R} \right] \Rightarrow \epsilon_x(y') = y' \frac{d^2 y}{dx^2}$$

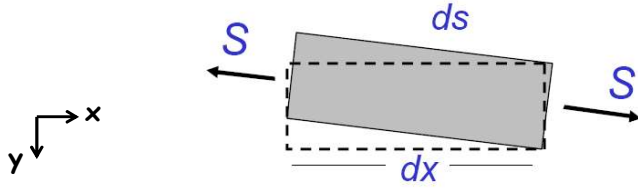
$$dW_{\text{bend}} = W dx \int_{-h/2}^{h/2} \frac{1}{2} E \left[y' \frac{d^2 y}{dx^2} \right]^2 dy' = \frac{1}{2} E \left(\frac{W h^3}{12} \right) \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

$$\therefore W_{\text{bend}} = \frac{1}{2} E I_z \int_0^L \left(\frac{d^2 y}{dx^2} \right)^2 dx$$

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Energy Due to Axial Load




- Strain due to axial load S contributes an energy dW_{stretch} in length dx , since lengthening of the different element dx (to ds) results in a strain ϵ_x

$ds = [(dx)^2 + (dy)^2]^{1/2} = dx \left[1 + \left(\frac{dy}{dx} \right)^2 \right]^{1/2} \xrightarrow{\text{Binomial Theorem}} dx \left[1 + \frac{1}{2} \left(\frac{dy}{dx} \right)^2 \right]$

$\therefore \epsilon_x = \frac{ds - dx}{dx} = \frac{1}{2} \left(\frac{dy}{dx} \right)^2$

$[dW_{\text{axial}} = S \epsilon_x dx = \frac{1}{2} S \left(\frac{dy}{dx} \right)^2 dx] \Rightarrow \boxed{W_{\text{axial}} = \frac{1}{2} S \int_0^L \left(\frac{dy}{dx} \right)^2 dx}$
 \nwarrow Axial Strain Energy

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Shear Strain Energy

$$W_{\text{shear}} = \frac{3(EI_z)^2}{4GWh} \int_0^L \left(\frac{d^3 y}{dx^3} \right)^2 dx$$

\nearrow Shear Modulus

- See W.C. Albert, "Vibrating Quartz Crystal Beam Accelerometer," Proc. ISA Int. Instrumentation Symp., May 1982, pp. 33-44

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Applying the Principle of Virtual Work

- Basic Procedure:**
 - Guess the form of the beam deflection under the applied loads
 - Vary the parameters in the beam deflection function in order to minimize:

$$U = \sum_j W_j - \sum_i F_i u_i$$

Sum strain energies

↑

Assumes point load

↓

↑

Displacement at point load
- Find minima by simply setting derivatives to zero
- See Senturia, pg. 244, for a general expression with distributed surface loads and body forces

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Example: Tapered Cantilever Beam

- Objective:** Find an expression for displacement as a function of location x under a point load F applied at the tip of the free end of a cantilever with tapered width $W(x)$
 - Top view of cantilever's $W(x)$

50% taper

$W(x) = W(1 - \frac{x}{2L_c})$
 - Adjustable parameters: minimize U
 - $y(x) = c_2 x^2 + c_3 x^3$
- Start by guessing the solution
 - It should satisfy the boundary conditions
 - The strain energy integrals shouldn't be too tedious
 - This might not matter much these days, though, since one could just use matlab or mathematica

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Strain Energy And Work By F

$U = \mathcal{W}_{bend} - F \cdot y(L_c)$

$$\mathcal{W}_{bend} = \frac{1}{2} E \int_0^{L_c} I_z(x) \left(\frac{d^2 y}{dx^2} \right)^2 dx \quad (\text{Bending Energy})$$

$$I_z(x) = \frac{W(x)h^3}{12} \quad \frac{d^2 y}{dx^2} = 2c_2 + 6c_3 x$$


(Using our guess)

$$W(x) = W \left(1 - \frac{x}{2L_c} \right)$$

Tip Deflection

$$= \frac{1}{24} E W h^3 \int_0^{L_c} \left(1 - \frac{x}{2L_c} \right) (2c_2 + 6c_3 x)^2 dx - F(c_2 L_c^2 + c_3 L_c^3)$$

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Find c_2 and c_3 That Minimize U


- Minimize $U \rightarrow$ basically, find the c_2 and c_3 that brings U closest to zero (which is what it would be if we had guessed correctly)
- The c_2 and c_3 that minimize U are the ones for which the partial derivatives of U with respect to them are zero:

$$\frac{\partial U}{\partial c_2} = 0 \quad \frac{\partial U}{\partial c_3} = 0$$

- Proceed:
 - ↳ First, evaluate the integral to get an expression for U :

$$U = E W h^3 \left\{ \frac{5c_3^2}{16} L_c^3 + \frac{c_2 c_3}{3} L_c^2 + \frac{c_2^2}{8} L_c \right\} - F(c_2 L_c^2 + c_3 L_c^3)$$

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Minimize U (cont)


- Evaluate the derivatives and set to zero:

$$\frac{\partial U}{\partial c_2} = 0 = \left(\frac{EWh^3}{3} c_3 - F \right) L_c^2 + \left(\frac{EWh^3}{4} c_2 \right) L_c$$

$$\frac{\partial U}{\partial c_3} = 0 = \left(\frac{5}{8} EWh^3 c_3 - F \right) L_c^3 + \left(\frac{EWh^3}{3} c_2 \right) L_c^2$$
- Solve the simultaneous equations to get c_2 and c_3 :

$$c_2 = \left(\frac{84}{13} \right) \frac{FL_c}{EWh^3} \quad c_3 = - \left(\frac{24}{13} \right) \frac{F}{EWh^3}$$

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The Virtual Work-Derived Solution


- And the solution:

$$y(x) = \left(\frac{24F}{13EWh^3} \right) \left(\left(\frac{7}{2} \right) L_c - x \right) x^2$$
- Solve for tip deflection and obtain the spring constant:

$$y(L_c) = \left(\frac{24F}{13EWh^3} \right) \left(\frac{5}{2} \right) L_c^3 \quad k_c = F / y(L_c) = \left(\frac{13EWh^3}{60L_c^3} \right)$$
- Compare with previous solution for constant-width cantilever beam (using Euler theory):

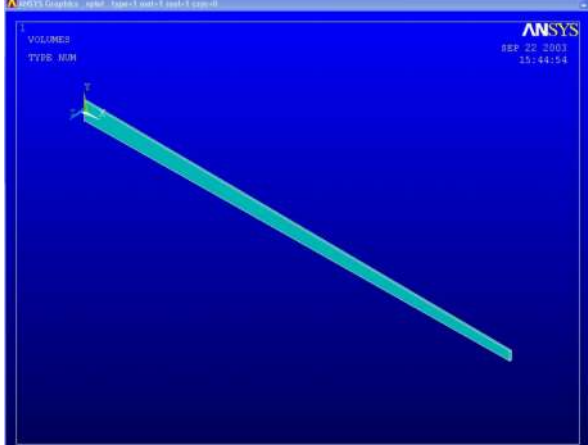
$$y(L_c) = \left(\frac{4F}{EWh^3} \right) L_c^3 \longrightarrow \text{13\% smaller than tapered-width case}$$

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Comparison With Finite Element Simulation

- Below: ANSYS finite element model with
 - $L = 500 \text{ } \mu\text{m}$ $W_{\text{base}} = 20 \text{ } \mu\text{m}$ $E = 170 \text{ GPa}$
 - $h = 2 \text{ } \mu\text{m}$ $W_{\text{tip}} = 10 \text{ } \mu\text{m}$



- Result:** (from static analysis)
 - $k = 0.471 \text{ } \mu\text{N/m}$
- This matches the result from energy minimization to 3 significant figures

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Need a Better Approximation?

- Add more terms to the polynomial
- Add other strain energy terms:
 - Shear: more significant as the beam gets shorter
 - Axial: more significant as deflections become larger
- Both of the above remedies make the math more complex, so encourage the use of math software, such as Mathematica, Matlab, or Maple
- Finite element analysis is really just energy minimization
- If this is the case, then why ever use energy minimization analytically (i.e., by hand)?
 - Analytical expressions, even approximate ones, give insight into parameter dependencies that FEA cannot
 - Can compare the importance of different terms
 - Should use in tandem with FEA for design

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